

EAST Search History

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|---|---|------------------|---------|------------------|
| S109 | 14 | (semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with (vapor or steam)) and ((sens\$3 or detect\$3) with (temperature and overheat\$3)) with control\$4 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 11:11 |
| S110 | 4 | ((semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with (vapor or steam)) and ((sens\$3 or detect\$3) with temperature) with control\$4).clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 11:09 |
| S108 | 1216 | (semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with (vapor or steam)) and ((sens\$3 or detect\$3) with temperature) with control\$4 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 11:08 |
| S107 | 4 | ((semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with vapor or steam) and ((sens\$3 or detect\$3) with temperature) with control\$4).clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 11:07 |
| S106 | 53 | (semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with vapor or steam) and ((sens\$3 or detect\$3) with temperature and overheat\$3) with control\$4 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 11:07 |
| S105 | 1356 | (semiconductor or wafer or substrate or workpiece) and (chamber or container or vessel) and (support\$3 or hold\$3) and (heat\$3 with (solvent or solution or water)) and (heat\$3 with vapor or steam) and ((sens\$3 or detect\$3) with temperature) with control\$4 | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 11:07 |

EAST Search History

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|----------|------|--|---|----|----|------------------|
| S10 3 | 28 | S101 and (heat\$3 and (sens\$3 or detect\$3) with temperature) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 11:02 |
| S10 4 | 52 | S102 and (heat\$3 and (sens\$3 or detect\$3) with temperature) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 10:58 |
| S10 2 | 493 | 134/58R,58R,95.2,98.1,99.1,102.1, 102.3,105,200,902.ccls. and @pd>"20041025" | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 10:56 |
| S10 1 | 222 | ((takayuki near2 toshima).in.) or ((kinya near2 ueno).in.) or ((miyako near2 yamasaka).in.) or ((hideyuki near2 tsutsumi).in.) or ((yuji near2 kamikawa).in.) and @pd>"20041025" | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 10:55 |
| S74 | 5050 | 134/58R,58R,95.2,98.1,99.1,102.1, 102.3,105,200,902.ccls. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 10:55 |
| S48 | 359 | ((takayuki near2 toshima).in.) or ((kinya near2 ueno).in.) or ((miyako near2 yamasaka).in.) or ((hideyuki near2 tsutsumi).in.) or ((yuji near2 kamikawa).in.) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/10/31 10:55 |